

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yukihiro Morita

Serial No.: 10/533,605

Filed: April 29, 2005

For: PLASMA DISPLAY PANEL AND
MANUFACTURING METHOD FOR THE
SAME

Patent Examiner:

Raabe, Christopher M.

Group Art Unit: 2879

Confirmation No.: 4549

April 27, 2007

Costa Mesa, California 92626

**SUPPLEMENTAL
INFORMATION DISCLOSURE STATEMENT**

Mail Stop Amendment
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In an attempt to fully comply with the duty of disclosure set forth in 37 C.F.R. § 1.56 and in conformance with 37 C.F.R. §§ 1.97 and 1.98, applicant wishes to bring to the attention of the U.S. Patent Office the following references, which were found during the prosecution of a corresponding European patent application:

U.S. Patent No. 6,379,783 Kim et al.

Japanese Patent Application Publication No. 08-236028 w/English abstract

Son Choongyong et al., "Stoichiometry dependency of the firing and sustain voltage properties of MgO thin films for alternating current plasma display panels", Journal of Vacuum Science and Technology A. Vacuum, Surfaces and Films, American Institute of Physics, New York, NY, US, vol. 17, no. 5, September 1999, pages 2619-2622.

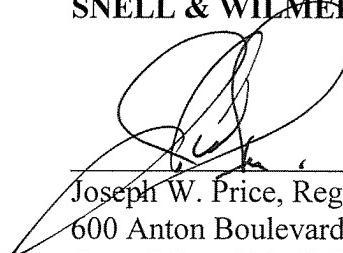
Copies of these references and Form PTO-A820 are attached.

The undersigned attorney hereby certifies that each item of information contained in the information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

If the Examiner believes that a telephone conference would help further the prosecution of this case, he is respectfully requested to contact the undersigned attorney at the listed telephone number.

Very truly yours,

SNELL & WILMER L.L.P.



Joseph W. Price, Reg. No. 25,124
600 Anton Boulevard, Suite 1400
Costa Mesa, CA 92626-7689
Tel: 714-427-7420
Fax: 714-427-7799

| INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i> | | | Docket Number (Optional) 92478-2600 | | Application Number 10/533,605 | | |
|---|-----|---|--|---------------------------|----------------------------------|----------|----------------------------|
| | | | Applicant(s) Yukihiro Morita | | | | |
| | | | Filing Date 04/29/2005 | | Group Art Unit 2879 | | |
| | | | U. S. PATENT DOCUMENTS | | | | |
| EXAMINER INITIAL | REF | DOCUMENT NUMBER | DATE | NAME | CLASS | SUBCLASS | FILING DATE IF APPROPRIATE |
| | | 6,379,783 | 4/30/2002 | Kim et al. | | | |
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| U. S. PATENT APPLICATION PUBLICATIONS | | | | | | | |
| EXAMINER INITIAL | REF | DOCUMENT NUMBER | DATE | NAME | CLASS | SUBCLASS | FILING DATE IF APPROPRIATE |
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| FOREIGN PATENT DOCUMENTS | | | | | | | |
| | REF | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | Translation |
| | | | | | | | YES |
| | | 08-236028 | 13.09.1996 | Japan w/ English abstract | | | X |
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| OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i> | | | | | | | |
| | | Son Choongyong et al., "Stoichiometry dependency of the firing and sustain voltage properties of MgO thin films for alternating current plasma display panels", Journal of Vacuum Science and Technology A. Vacuum, Surfaces and Films, American Institute of Physics, New York, NY, US, vol. 17, no. 5, September 1999, pages 2619-2622. | | | | | |
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| EXAMINER | | | DATE CONSIDERED | | | | |
| EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | | | | | | | |